



JAN 26 2004

Attorney Docket No. UMC-96-279  
Client Matter No. 81848.0016

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Regarding U.S. Patent No. 6,117,345 to:

Chih-Chien LIU, et al.

Issued: September 12, 2000

Serial No. 08/958,460

Filed: October 28, 1997

For: HIGH DENSITY PLASMA CHEMICAL  
VAPOR DEPOSITION PROCESS

Certificate

FEB 03 2004

of Correction

CERTIFICATE OF MAILING BY EXPRESS MAIL

ATTENTION: Certificate of Corrections Branch  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

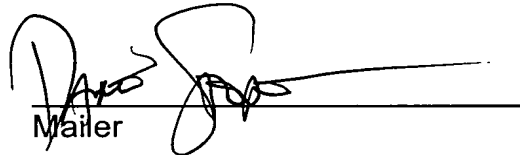
Sir:

The undersigned hereby certifies that the attached

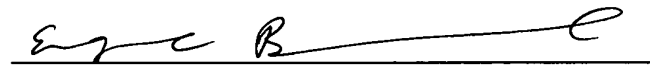
1. Request for Certificate of Correction of Patent For Applicant's Mistake Under 37 C.F.R. 1.323;
2. Certificate of Correction (2 originals);
3. Return Card, and

this Certificate of Mailing by Express Mail relating to the above application, were deposited as "Express Mail", Mailing Label No. EL533429462US with the United States Postal Service, addressed to ATTENTION: Certificate of Corrections Branch Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on January 22, 2004.

January 22, 2004

  
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